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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
09/757,529	01/11/2001	Toshihiro Mori	018775-814	8100	
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Platon N. Mandros			BALI, VIKKRAM		
BURNS, DOAI	NE, SWECKER & MATI	HIS, L.L.P.			
P.O. Box 1404			ART UNIT	PAPER NUMBER	
Alexandria, VA 22313-1404			2623		
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Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)		
Office Action Summary		09/757,529	MORI, TOSHIHIRO		
		Examiner	Art Unit		
•		Vikkram Bali	2623		
The MAILING DA	TE of this communication app	pears on the cover sheet with the	correspondence address		
WHICHEVER IS LONGI - Extensions of time may be avail after SIX (6) MONTHS from the - If NO period for reply is specifie - Failure to reply within the set or	ER, FROM THE MAILING D able under the provisions of 37 CFR 1.1 mailing date of this communication. d above, the maximum statutory period v extended period for reply will, by statute later than three months after the mailing	Y IS SET TO EXPIRE 3 MONTH ATE OF THIS COMMUNICATIO 36(a). In no event, however, may a reply be time will apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE g date of this communication, even if timely file	N. mely filed n the mailing date of this communication. ED (35 U.S.C. § 133).		
Status					
2a)⊠ This action is FINA 3)□ Since this applicat	tion is in condition for allowa	flay 2005. s action is non-final. nce except for formal matters, pr Ex parte Quayle, 1935 C.D. 11, 4			
Disposition of Claims					
4a) Of the above of 5) ☐ Claim(s) is 6) ☐ Claim(s) <u>1-26</u> is a 7) ☐ Claim(s) <u>27-29</u> is a first of the above of the	re rejected.	wn from consideration.			
Application Papers					
10) The drawing(s) file Applicant may not re Replacement drawing	equest that any objection to the ng sheet(s) including the correct	er. cepted or b) objected to by the drawing(s) be held in abeyance. Se tion is required if the drawing(s) is ol xaminer. Note the attached Office	ee 37 CFR 1.85(a). bjected to. See 37 CFR 1.121(d).		
Priority under 35 U.S.C. §	119				
 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of: 1. Certified copies of the priority documents have been received. 2. Certified copies of the priority documents have been received in Application No. 3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)). * See the attached detailed Office action for a list of the certified copies not received. 					
	ent Drawing Review (PTO-948) ment(s) (PTO-1449 or PTO/SB/08)	4) Interview Summar Paper No(s)/Mail D 5) Notice of Informal 6) Other:			

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DETAILED ACTION

In response to the amendment filled on 5/23/2005, all the amendments have been entered, and the action follows:

Claim Rejections - 35 USC § 103

- 1. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 2. Claims 16-26 are rejected under 35 U.S.C. 103(a) as being unpatentable over Maruo (US 6292583) in view of Kametani et al (US 6538248).

Regarding Claim 16, Maruo discloses a specified pattern recognition apparatus comprising:

a plurality of filters provided for detecting an image at a first resolution (Figure 1, Step S1, Two-dimensional wavelet-transform; Column 6, Lines 57-67, Column 7, Lines 1-51. Wavelet transform comprises a plurality of low-pass and high –pass filtering.);

an extractor which extracts a specified pattern included in the image with use of a combination of filters in said plurality of filters to determine a position of the specified pattern (Figures 5 and 6; Column 7, Lines 34-51. Edge components of the input signal have been extracted by wavelet transformation.);

a circuit for generating an image of the specified pattern at a resolution lower than the first resolution (Figure 1, Step S2, Binarization Process. In addition to the different lower resolution images generated by the wavelet transform, binarization process will further generate an image of lower optical resolution.):

a calculator which determines the position of the specified pattern more precisely than said extractor, based on the position determined by said extractor and the lower resolution image (Figure 1, Step S3, Hough-Transform; Column 5, Lines 59-63; Column 6, Lines 3-56).

However, Maruo fails to disclose determine of position and the rotation as claimed. Kametani teaches the calculating of the position and the rotation (see col. 14, lines 25-35, calculating of the position and the rotation of the specified pattern) as claimed. It would have been obvious to one ordinary skilled in the art at the time of invention to combine the two references as they are analogous because they are solving similar problem of inspection. The determining of the position and the rotation of the specified pattern as taught by Kametani can be introduce in to the Maruo's system and that provides a system for detecting errors in the target specified pattern.

With regards to Claim 17, arguments analogous to those presented for Claim 16 are applicable to Claim 17. Maruo further discloses:

an image extractor which extracts partial images included in the specified pattern, in the bi-level image data obtained by said binarizer (Figures 3, 7 and 8; Column 8, Lines 30-57. The circle is the extracted partial image.);

a reduced image generator which generates a reduced image of an image including the specified partial image, the reduced image having a lower resolution than the image including the specified images (Figures 8 and 15, Wavelet transform inherently generates lower resolution image of the specified partial image (The circle).).

However, Maruo fails to disclose determine of position and the rotation as claimed. Kametani teaches the calculating of the position and the rotation (see col. 14, lines 25-35, calculating of the position and the rotation of the specified pattern) as claimed. It would have been obvious to one ordinary skilled in the art at the time of invention to combine the two references as they are analogous because they are solving similar problem of inspection. The determining of the position and the rotation of the specified pattern as taught by Kametani can be introduce in to the Maruo's system and that provides a system for detecting errors in the target specified pattern.

Regarding Claim 20, Maruo further discloses the specified pattern detection apparatus according to Claim 16, wherein the plurality of filters are providing for extracting a plurality of specified patterns(Figures 5 and 6; Column 7, Lines 34-51. Edge components of the input signal have been extracted by wavelet transformation.).

With regards to Claim 21, arguments analogous to those presented for Claim 20 are applicable to Claim 21.

With regards to Claim 22, arguments analogous to those presented for Claim 16 are applicable to Claim 22.

With regards to Claim 23, arguments analogous to those presented for Claim 17 are applicable to Claim 23.

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Regarding Claim 24, Maruo discloses a specified pattern detection apparatus Comprising:

a binarizer which binarizes input image data to provide bi-level image data

(Figures 1 and 2, Binarization process; Column 5, Lines 57-67, Column 6, Lines 1-5);

a storage device which stores the bi-level image data obtained by said binarizer

(Figure 11, RAM 34);

a partial image extractor which extracts specified partial images in the bi-level image stored in said storage device with a filter for conversion (Figures 1 and 2, Hough transform; Column 6, Lines 5-6);

a gain calculator which calculates and stores information for each pixel in the bilevel image, in which the specified partial images are extracted, with a gain filter, the information representing a distance from the each pixel to the specified partial image (Column 6, Lines 5-20; Formulas (1) and (2));

a position calculator which calculates ideal positions of the partial images to be included in a specified pattern (Column 6, Lines 22-56; Column 9, Lines 12-23; Figure 3A; Column 10, Lines 46-67, Column 11, Lines 1-21; Column 13, Lines 23-51); and

a gain output device which outputs a gain on the ideal positions based op the information obtained and stored by said gain calculator (Figure 3A; Column 10, Lines 46-67, Column 11, Lines 1-21). However, he fails to explicitly disclose the specified pattern as claimed. Kametani teaches the inspection of the wafer wherein the specified pattern is use (see col. 7, lines 25-35, the specified is the chips on the substrate) as claimed, . It would have been obvious to one ordinary skilled in the art at the time of

invention to combine the two references as they are analogous because they are solving similar problem of inspection. The determining of the position and the rotation of the specified pattern as taught by Kametani can be introduce in to the Maruo's system and that provides a system for detecting errors in the target specified pattern Regarding Claim 25, Maruo further discloses the specified pattern detection apparatus according to Claim 24, wherein said conversion filter converts the partial image stored in said storage device to 1-bit data (Figures 1B and 1C; Column 9, Lines 24-58). With regards to Claim 26, arguments analogous to those presented for Claim 24 are applicable to Claim 26.

Regarding Claims 18 and 19, Maruo discloses wavelet transform of the input image (convolving the image by a plurality of filters, i.e., filtering in horizontal, diagonal and vertical directions) for outputting detailed information on image data (high-pass information which corresponds to the edge data; Column 7, Lines 46).

Maruo does not explicitly disclose the filters in the combination of filters are positioned along a circumferential line. However, it is well known that detected edges are the boundaries of patterns in the image which indicates that filtering is ultimately performed on the circumferential lines (Official Notice).

It would have been obvious to a person of ordinary skill in the art at the time the invention was made to modify Maruo's invention to position filters along a circumferential line because it is a standard procedure to recognize image contours or boundaries which will improve the accuracy of pattern recognition system.

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Allowable Subject Matter

3. Claims 27-29 are objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims.

Response to Arguments

4. Applicant's arguments with respect to claims 1-26 have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

5. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

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Any inquiry concerning this communication or earlier communications from the examiner should be directed to Vikkram Bali whose telephone number is 571.272.7415. The examiner can normally be reached on 7:00 AM - 3:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Amelia Au can be reached on 571.272.7414. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Vikkram/Bath / V Primary/Examiner

vb September 28, 2005